



IFW

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Koichi KANAYA et al.

Group Art Unit: 1762

•Application No.: 10/565,653

Examiner: K. CHEN

Filed: January 24, 2006

Docket No.: 126247

For: VAPOR DEPOSITION APPARATUS AND VAPOR DEPOSITION METHOD

AMENDMENT UNDER 37 CFR §1.111

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In reply to the January 14, 2009 Office Action and the April 2 personal interview,
please consider the following:

Amendments to the Claims as reflected in the listing of claims; and

Remarks.